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ABSTRACT

2 A substrate transport apparatus comprising a drive
3 section and a robot transport arm. The robot transport
4 arm is mounted to the drive section. The robot transport
5 arm has a wrist and an end effector to hold the substrate
6 thereon. The end effector is rotatably mounted to the
7 wrist to rotate about the wrist. The rotation of the end
8 effector about the wrist is slaved to the robot transport
9 arm. The robot transport arm is adapted to transport
10 substrates into and out of two general side-by-side
11 orientated substrate holding areas with the drive section
12 being located in only one location relative to the two
13 holding areas.

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